

MIP ENABLED PFAS SENSOR

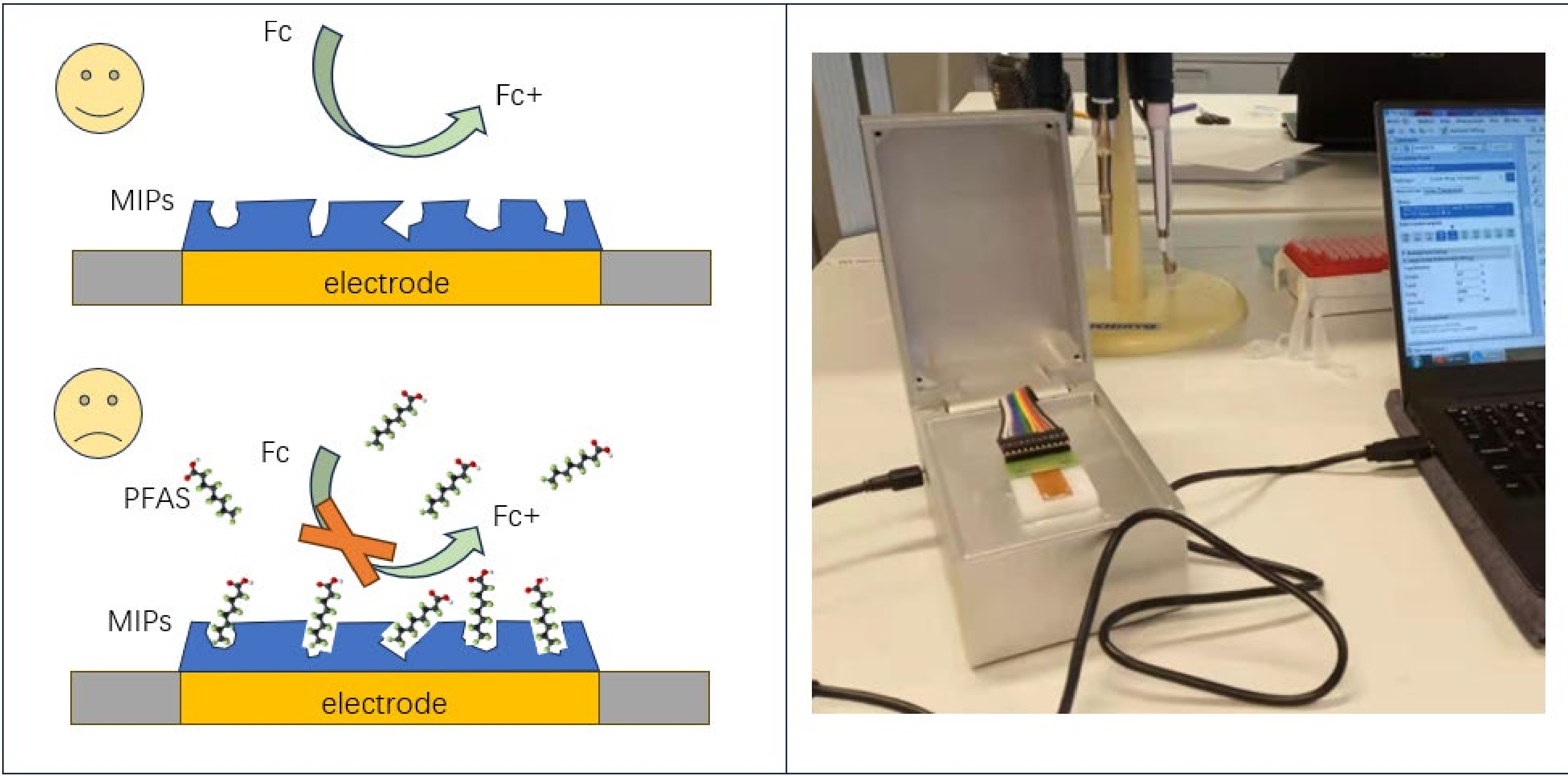
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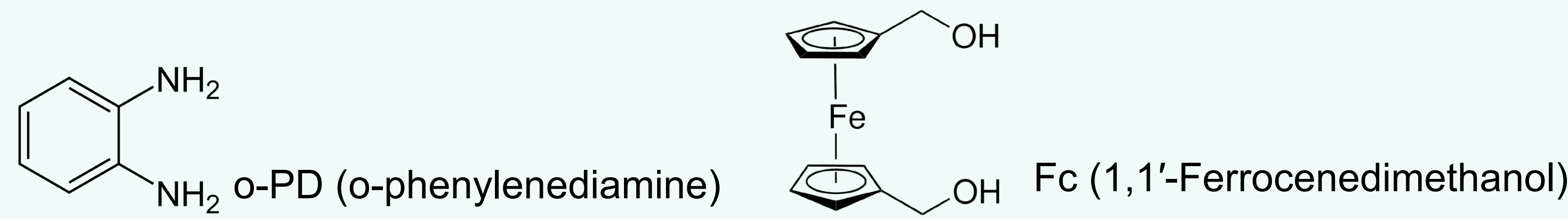
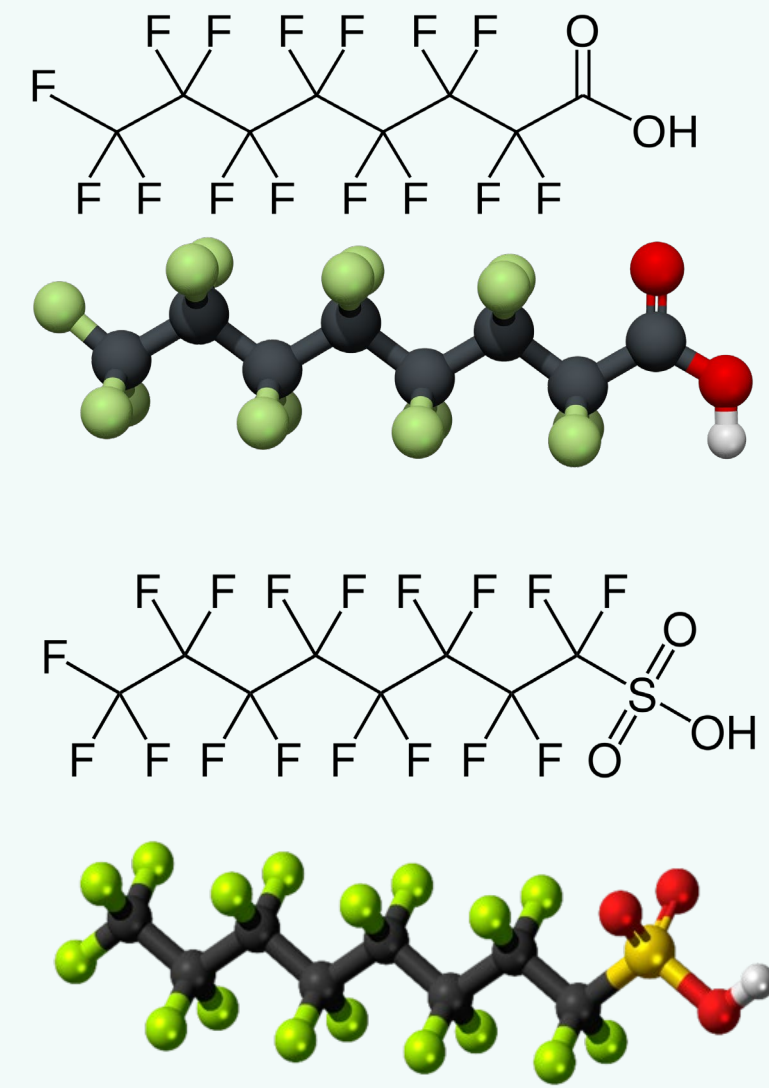
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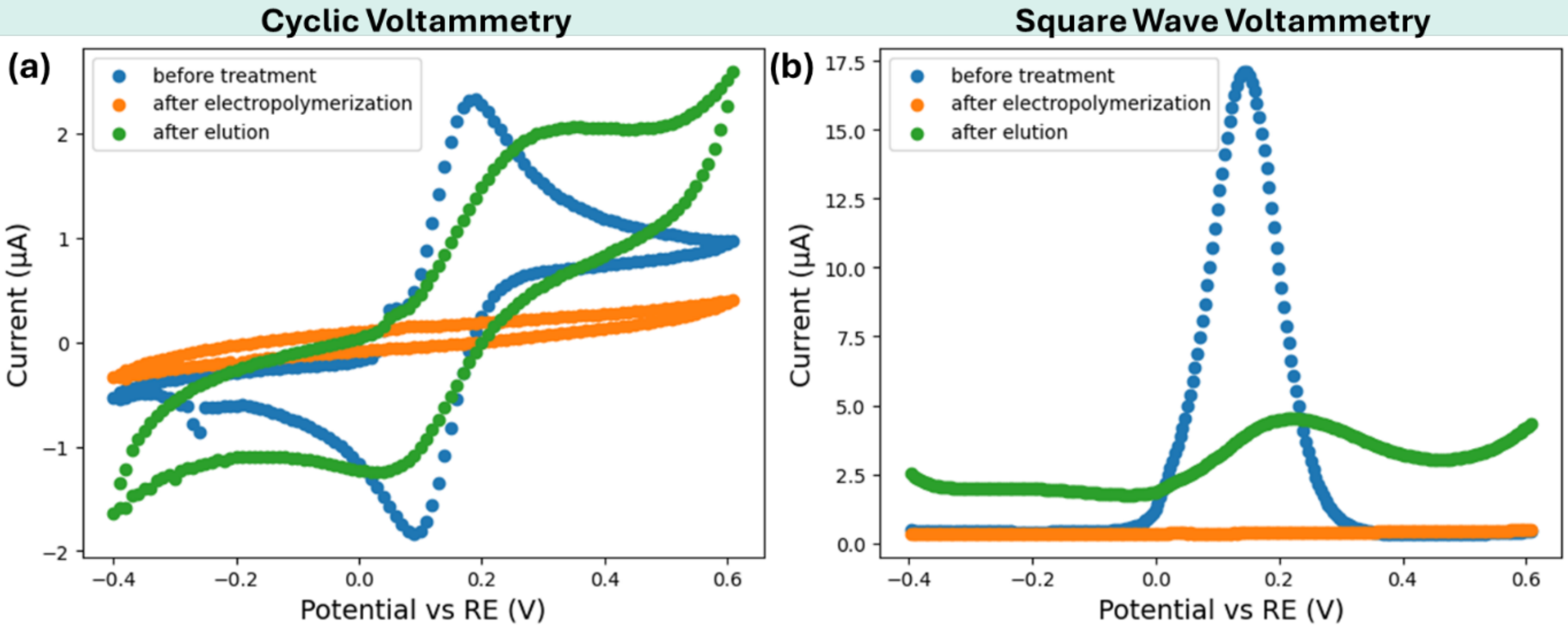
Introduction



- ❖ PFAS (Per- and polyfluoroalkyl substances) are persistent contaminants with background levels of 1.4 µg/kg **PFOS** (Perfluorooctanesulfonic acid) and 1.9 µg/kg **PFOA** (Perfluorooctanoic acid) in Dutch soil [1].
- ❖ Current lab methods (e.g., chromatography coupled with mass spectroscopy) are expensive and slow (~200 pM detection limit) [2-3].
- ❖ Goal: Develop a portable MIP-based (Molecularly Imprinted Polymer) electrochemical PFAS sensor for on-site detection.
- ❖ Method: MIP sensing uses electro-polymerized o-PD (o-phenylenediamine) to create selective cavities for PFAS, reducing redox mediator (Fc, 1,1'-Ferrocenedimethanol) current upon rebinding.

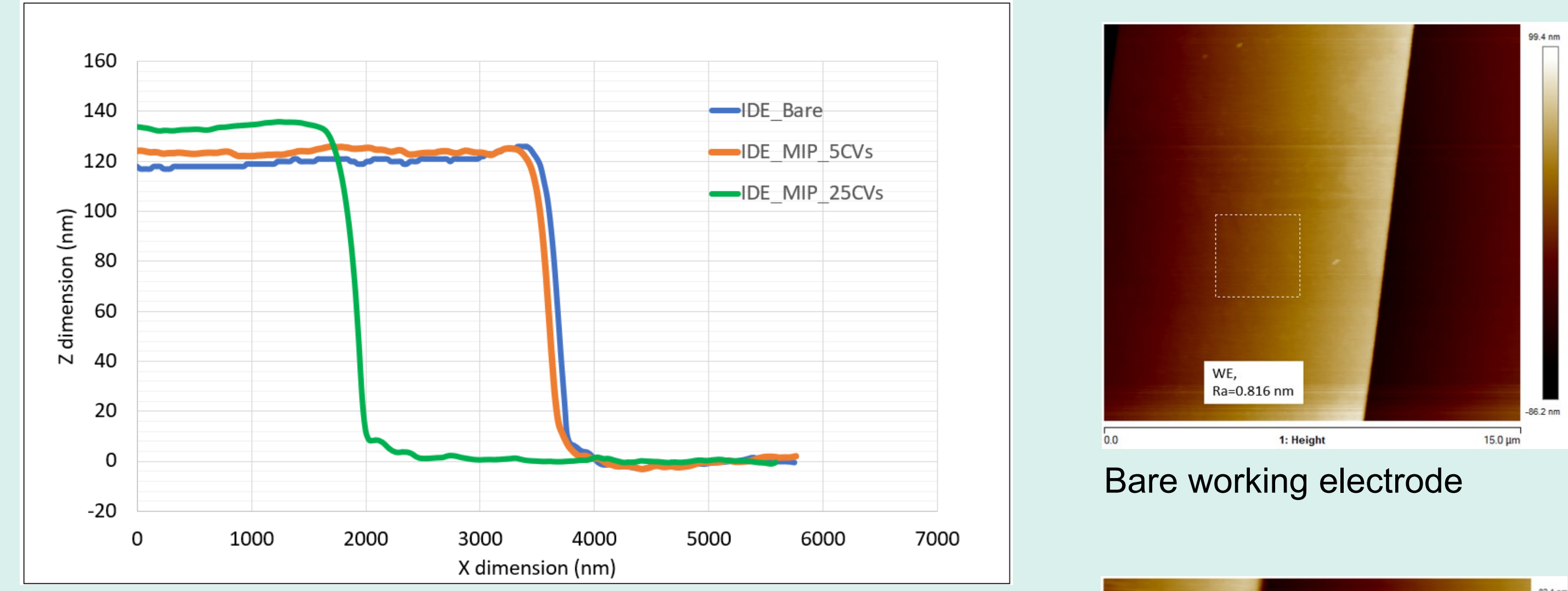


MIP Electro-Polymerization



CV (left, cyclic voltammetry) and SWV (right, square wave voltammetry) measurements of the MIP formation on a CSPE (carbon screen printed electrode), performed in 2 mM Fc with 10 mM ammonia buffer pH 8.4.

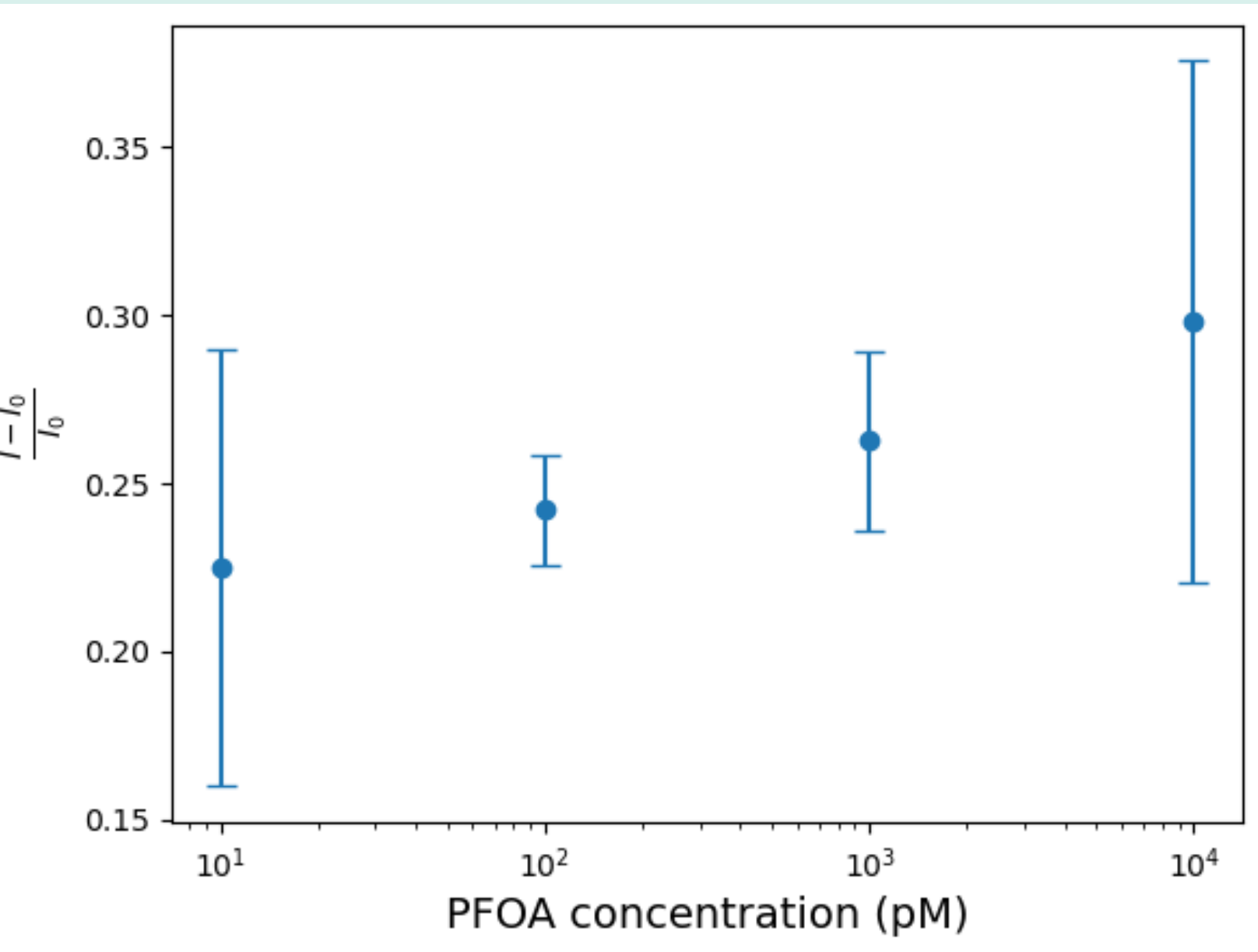
AFM (Atomic Force Microscopy)



AFM measurements on a bare IDE, IDEs with 5 and 25 cycles of electropolymerization.

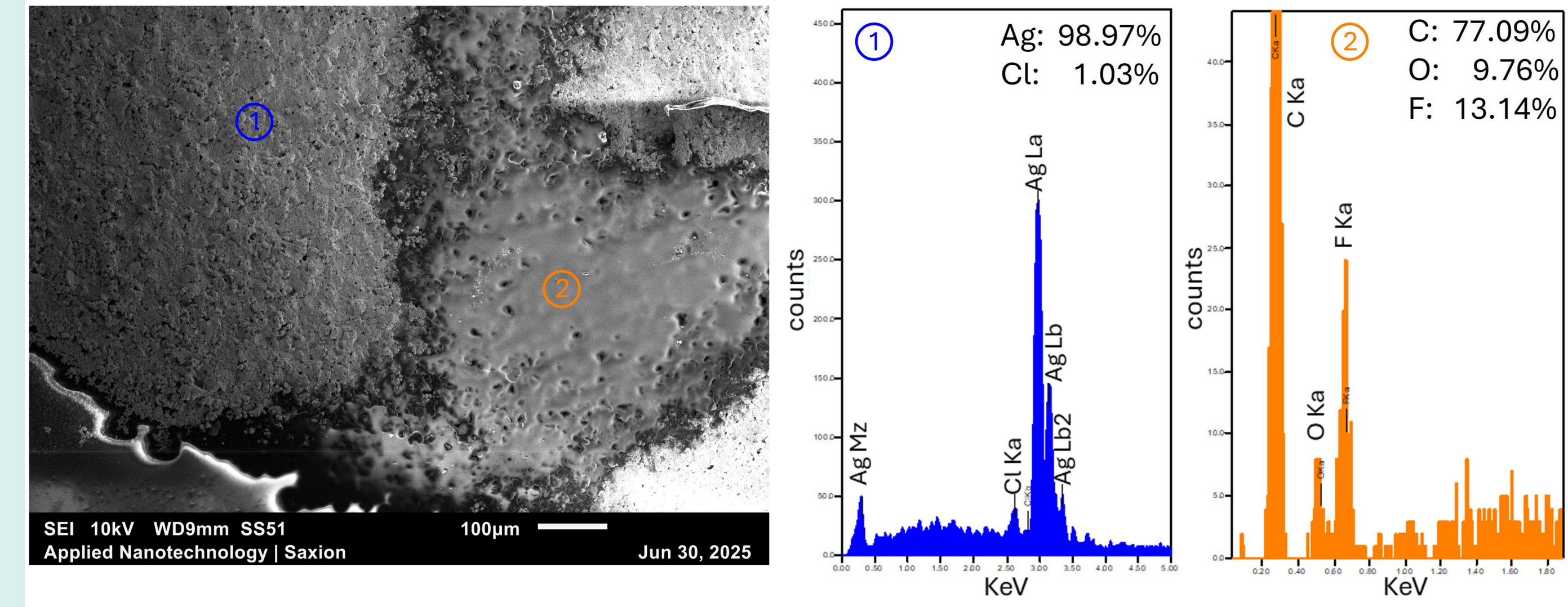
- ❖ AFM assessed MIP thickness on IDE (interdigitated electrodes), at 4-20 nm.
- ❖ Thickness correlates with electro-polymerization voltammetry cycles, 5 and 25 cycles (a cycle process lasts 40 seconds).
- ❖ Roughness of MIP coating is significantly higher than bare electrode.

PFOA Rebinding Test



Normalized peak current changes from SWV (square wave voltammetry) measurements vs. PFOA concentrations, performed in 2 mM Fc and 10 mM ammonia buffer pH 8.4 spiked with various PFOA concentrations with an incubation time of 30 minutes.

SEM-EDS (Scanning Electron Microscopy with Energy Dispersive X-ray)



Left: SEM image of the Ag/AgCl counter electrode of a CSPE with a layer of PFOA. Right: Results of a SEM-EDS measurement on 2 different locations.

- ❖ SEM-EDS can be used to measure thick PFOA layer.
- ❖ The MIP layer is too thin to be analyzed, as the SEM-EDS has a measuring depth of around 500 - 3000 nm.

Conclusions

- ❖ MIP layers were prepared on various electrodes with stable electrochemical signals.
- ❖ Varying the electropolymerization time gives control over the thickness of the MIP layer.
- ❖ Challenges: Unexpected signal upon sensing PFOA, and SEM-EDS limitations.

Future Work

- ❖ Experiments: Test PFOS with adjusted concentrations.
- ❖ Techniques: Use EIS and SEM-EDS for better characterization.
- ❖ Adjustments: Explore other PFAS and MIP agents.

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